

Form PTO-1449

Docket Number (Optional)

Application Number

TSMC-02-218

10/689,431

Applicant

Hung-Dar Su et al.

Filing Date

10/20/03

Group Art Unit

2829

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

U. S. PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	ALING DATE IF APPROPRIATE
MT	5485097	1/16/96	Wang	324	765	8/8/94
	6456105	9/24/02	Tao	324	769	8/8/00
	6472236	10/29/02	Wang et al.	438	14	7/13/01
	6066952	5/23/00	Nowak et al.	324	458	9/25/97
	5793675	8/11/98	Cappellotti et al.	365	185.09	4/1/97
	6339339	1/15/02	Maeda	324	769	1/22/01
	6472233	10/29/02	Ahmed et al.	438	14	6/5/00
MT	6011404	1/4/00	Ma et al.	324	765	7/3/97

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Part/Part Pages, Etc.)

MT	-	"Gate Dielectric Capacitance-Voltage Characterization Using the Model 4200 Semiconductor Characterization System", Keithley, Application Notes Series, No. 2239. (no month/year)
	-	Agilent Technologies Impedance Measurement Handbook, 2nd Edition, Application Note 5950, staff, Agilent Technologies Co., Ltd., Palo Alto, CA, Copyright 2000, 5-12 to 5-14. (no month)
MT		

EXAMINER

DATE CONSIDERED

Muh Tang

01/05/05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

